

**Supplementary Information**

**High electrical conduction of Sb square net in anti-ThCr<sub>2</sub>Si<sub>2</sub> type La<sub>2</sub>O<sub>2</sub>Sb thin  
film grown by multilayer solid-phase epitaxy**

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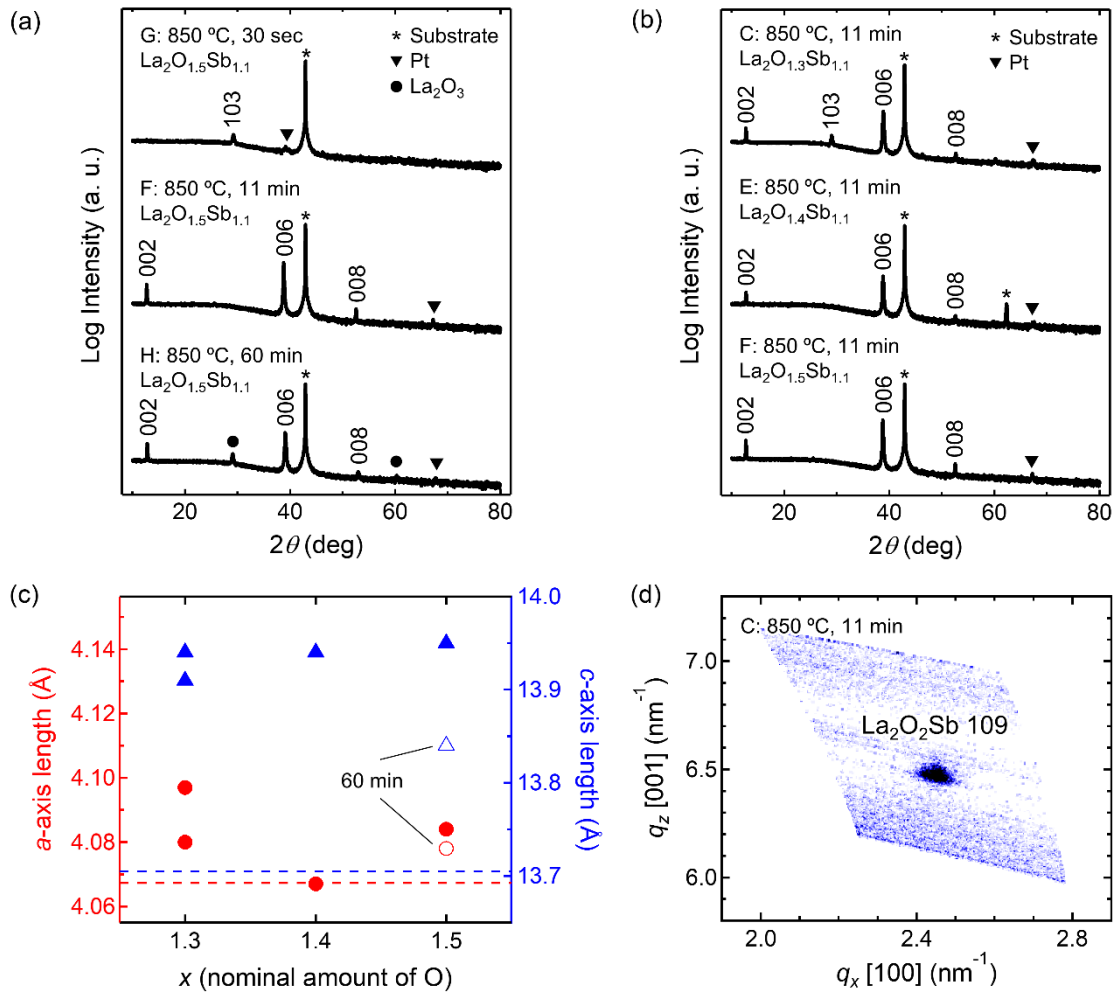
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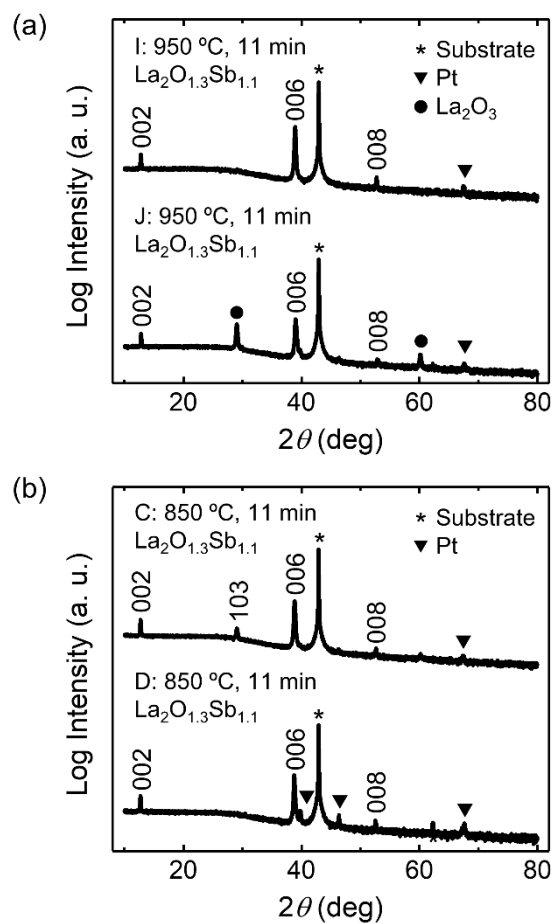
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**Table S1** Summary of growth condition, chemical composition, crystal structure parameters, and the correspondence with figures for the La<sub>2</sub>O<sub>2</sub>Sb epitaxial thin films.

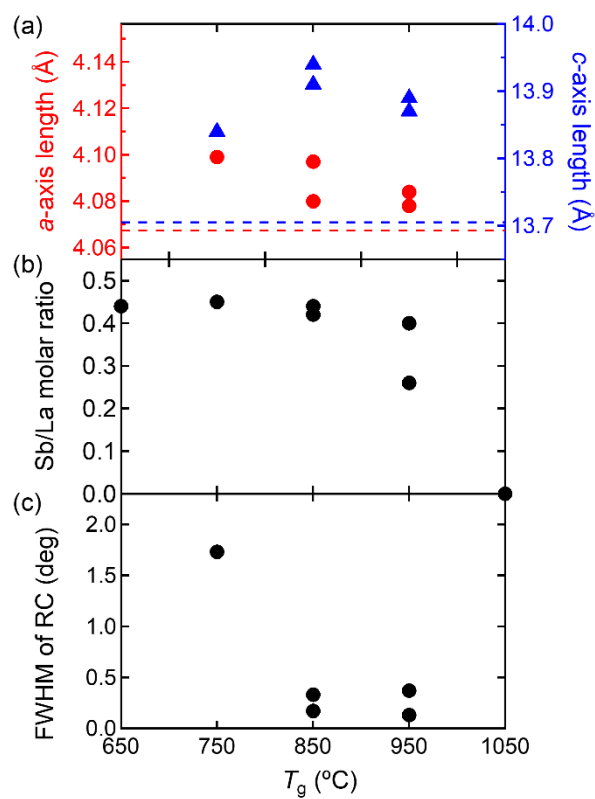
Sample	Multilayer precursor (nominal composition)	$T_g$	Heating time	Sb/La molar ratio	<i>a</i> -axis length (Å)	<i>c</i> -axis length (Å)	FWHM of RC (deg)	Figures
A	[La <sub>2</sub> O <sub>3</sub> (5.1 nm)/La (19 nm)/La <sub>2</sub> O <sub>3</sub> (5.1 nm)/Sb (27 nm)] <sub>2</sub> (La <sub>2</sub> O <sub>1.3</sub> Sb <sub>1.1</sub> )	650 °C	11 min	0.44	-	-	-	Fig. 2a, 3, S3
B		750 °C		0.45	4.099	13.84	1.73	Fig. 2a, 3, S3
C		850 °C		0.42	4.097	13.91	0.33	Fig. 2a, 3, 6, S1b, S1c, S1d, S2b, S3, S5, S6
D				0.44	4.080	13.94	0.17	Fig. S1c, S2b, S3, S4, S5, S6
E	[La <sub>2</sub> O <sub>3</sub> (5.5 nm)/La (18 nm)/La <sub>2</sub> O <sub>3</sub> (5.5 nm)/Sb (27 nm)] <sub>2</sub> (La <sub>2</sub> O <sub>1.4</sub> Sb <sub>1.1</sub> )	850 °C	11 min	0.45	4.067	13.94	0.35	Fig. 2b, 2c, 5, S1b, S4
F	0.44			4.078	13.95	0.17	Fig. S1a, S1b, S1c, S5, S6	
G	[La <sub>2</sub> O <sub>3</sub> (6.2 nm)/La (16 nm)/La <sub>2</sub> O <sub>3</sub> (6.2 nm)/Sb (27 nm)] <sub>2</sub> (La <sub>2</sub> O <sub>1.5</sub> Sb <sub>1.1</sub> )			30 sec	0.35	-	-	Fig. S1a, S1c
H			60 min	0.36	4.084	13.84	0.16	Fig. S1a, S1c
I	[La <sub>2</sub> O <sub>3</sub> (5.1 nm)/La (19 nm)/La <sub>2</sub> O <sub>3</sub> (5.1 nm)/Sb (27 nm)] <sub>2</sub> (La <sub>2</sub> O <sub>1.3</sub> Sb <sub>1.1</sub> )	950 °C	11 min	0.40	4.078	13.89	0.13	Fig. 2a, 3, 4, 6, S2a, S3, S5
J				0.26	4.084	13.87	0.37	Fig. S2a, S3
K	[La <sub>2</sub> O <sub>3</sub> (5.1 nm)/La (19 nm)/La <sub>2</sub> O <sub>3</sub> (5.1 nm)/Sb (27 nm)] <sub>2</sub> (La <sub>2</sub> O <sub>1.3</sub> Sb <sub>1.1</sub> )	1050 °C		0.00	-	-	-	Fig. 2a, 3, S3



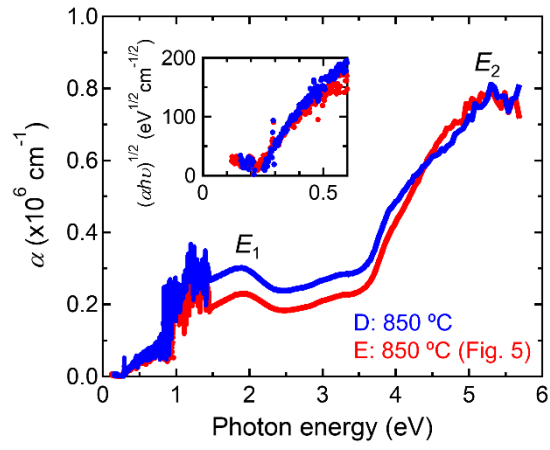
**Fig. S1** Out-of-plane XRD patterns of the films on MgO (001) substrates for different (a) heating time (30 sec, 11 and 60 min) and (b) nominal amount of oxygen with  $T_g = 850^\circ\text{C}$ . The chemical formulae denote the nominal composition. (c) The  $a$ - (circle) and  $c$ - axis lengths (triangle) as a function of nominal amount of oxygen. Red and blue dashed lines represent  $a$ - and  $c$ - axis lengths of  $\text{La}_2\text{O}_2\text{Sb}$  bulk polycrystal, respectively.<sup>S1</sup> (d) Reciprocal space mapping of the  $\text{La}_2\text{O}_2\text{Sb}$  epitaxial thin film with  $T_g = 850^\circ\text{C}$ .



**Fig. S2** Out-of-plane XRD patterns of the obtained films on MgO (001) substrates with (a)  $T_g = 950$  °C and (b) 850 °C for two different runs.

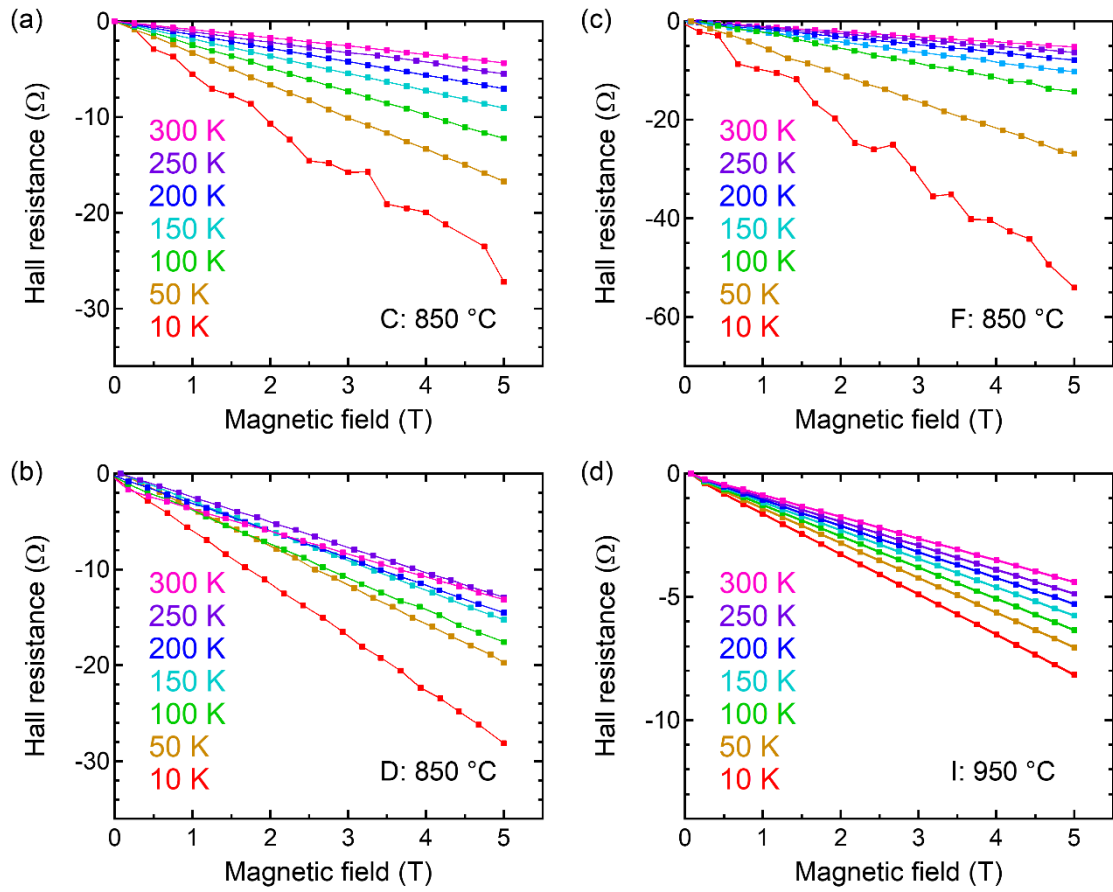


**Fig. S3** Growth temperature ( $T_g$ ) dependence of (a) *a*- (circle) and *c*- axis lengths (triangle), (b) Sb/La molar ratio, and (c) FWHM of rocking curve (RC) for 006 diffraction peak of the  $\text{La}_2\text{O}_2\text{Sb}$  epitaxial thin films. Red and blue dashed lines in (a) denote *a*- and *c*- axis lengths of  $\text{La}_2\text{O}_2\text{Sb}$  bulk polycrystal, respectively.

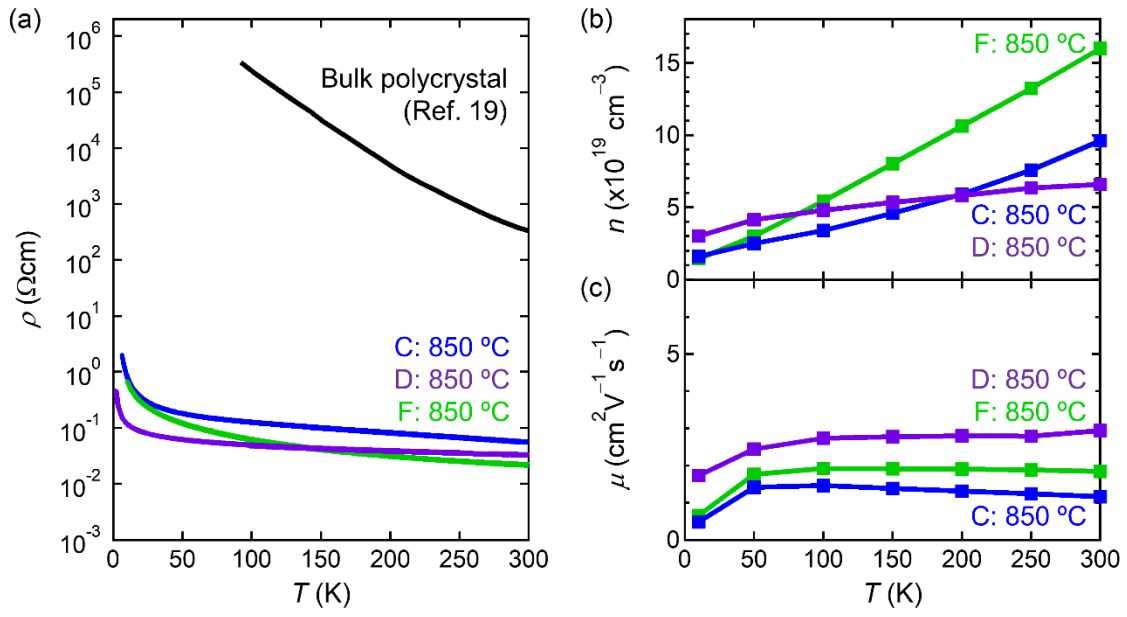


**Fig. S4** Absorption coefficient spectra for two different  $\text{La}_2\text{O}_2\text{Sb}$  epitaxial thin films with  $T_g = 850\text{ }^\circ\text{C}$ .

Upper inset shows Tauc plot of the absorption edge.



**Fig. S5** Magnetic field dependence of Hall resistance for the  $\text{La}_2\text{O}_2\text{Sb}$  epitaxial thin films with (a)–(c)  $T_g = 850\text{ }^\circ\text{C}$  and (d)  $950\text{ }^\circ\text{C}$ . The data scattering in the Hall resistance at 10 K in (a) and (c) was caused by the measurement limit due to the high resistance of the films.



**Fig. S6** Temperature dependence of (a) resistivity, (b) carrier density, and (c) carrier mobility for the La<sub>2</sub>O<sub>2</sub>Sb epitaxial thin films with  $T_g = 850$  °C.



References in supplementary information

- S1. P. L. Wang, T. Kolodiaznyi, J. Yao, Y. Mozharivskyj, *J. Am. Chem. Soc.* 2012, **134**, 1426.